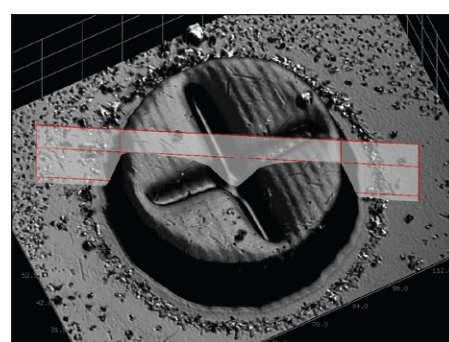
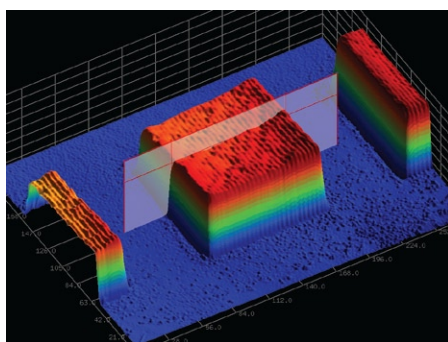
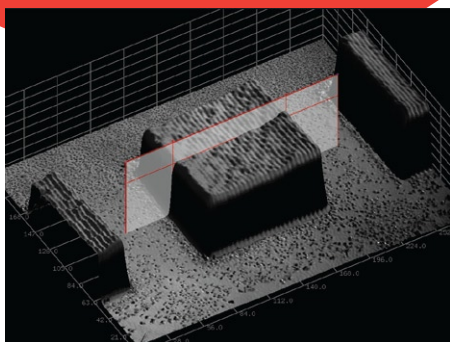


High Speed 3D Confocal Laser Scanning Module

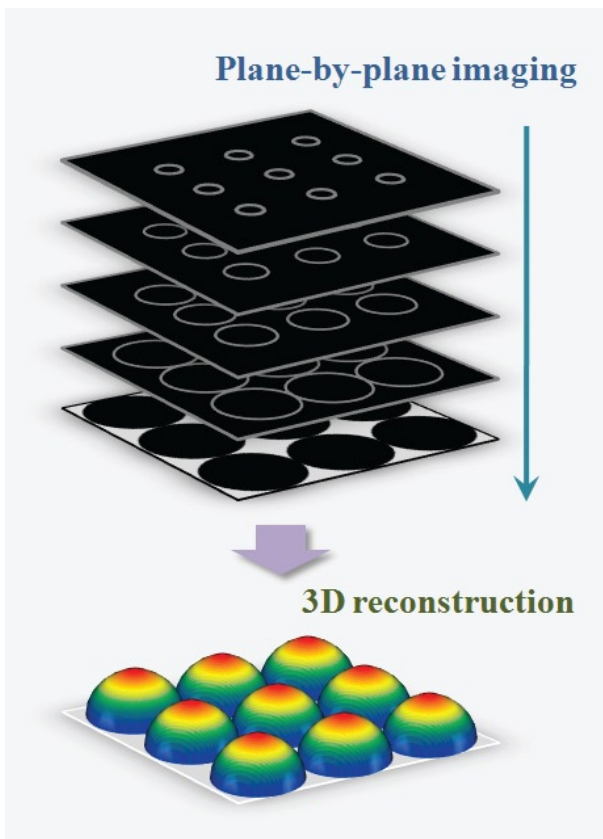
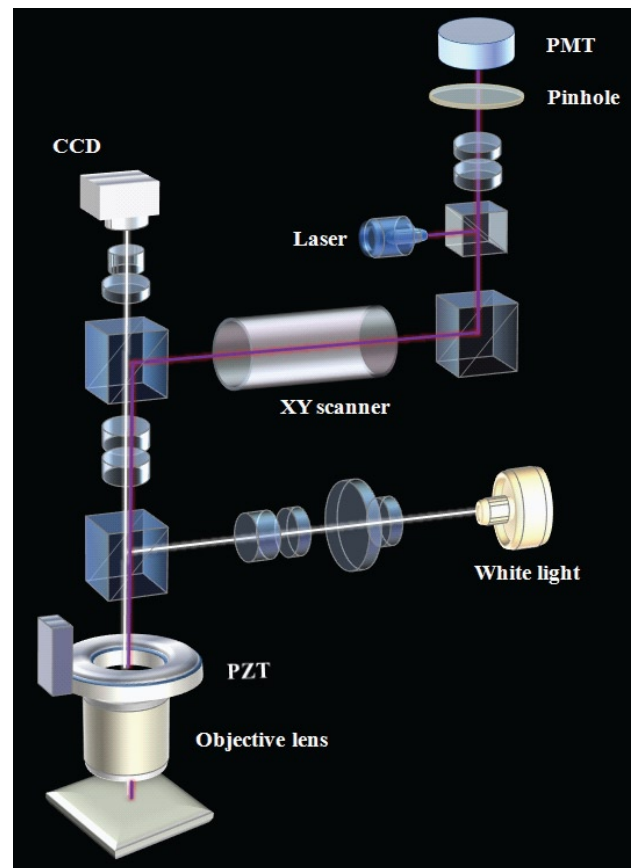
NS-3800



Measurement principle

NS-3800 provides a color CCD image and a laser scanning confocal image at one time.

The height measuring ability comes from the confocal arrangement of a source, a sample, and a detector. By the out-of-focus signal rejection of confocal technique, only the in-focus signal is collected by a photo detector. It gives the optical sectioning ability to confocal microscope NS-3800. The confocal aperture also improves the imaging quality by rejecting the noise outside the focal point.

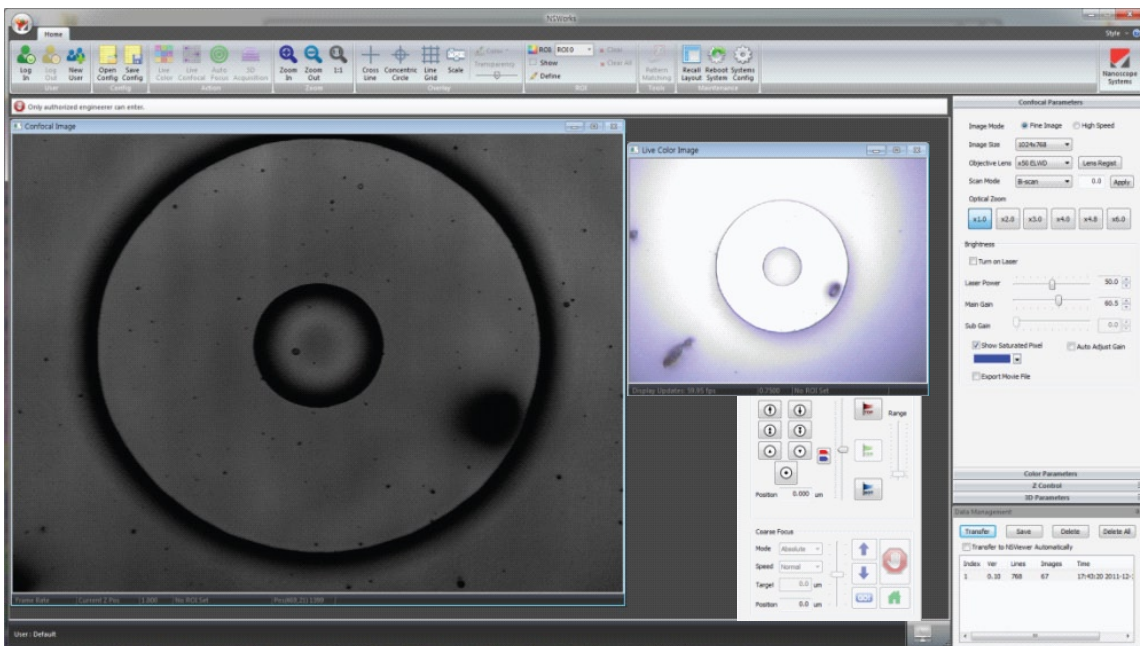


To get the 3D surface profile of the sample, optically sectioned plane-images are collected along the z-axis. As the light intensity becomes its maximum when the sample surface is placed in the focal plane, axial coordinates of sample surface can be directly found.

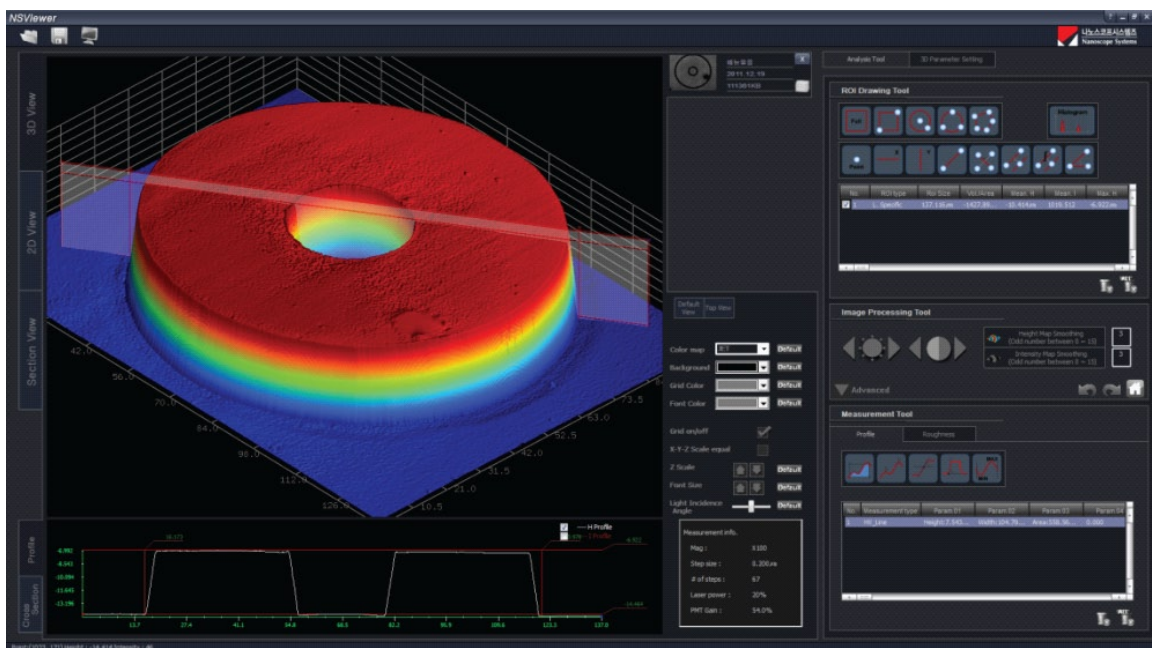
With a violet laser, a photo-multiplier tube (PMT), and a piezoelectric axial scanner, NS-3800 performs the confocal optical sectioning in a most reliable manner.

User interface software *NSWorks* & *NSViewer*

- Simple and plain operation even to a first-time user.
- A CCD image, a confocal image, and a main control panel are displayed in one operation window.
- Various adjustable parameters are provided for the advanced application.
- A real-time confocal image provides the immediate feedback from hardware.
- Separated analysis window with the convenient graphical reporting tools.
- The 3D graphical view makes a user easily recognize the microscopic structure of a sample.



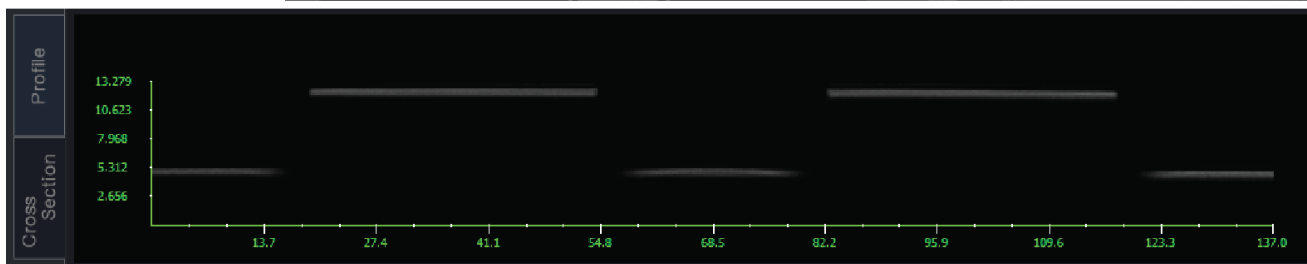
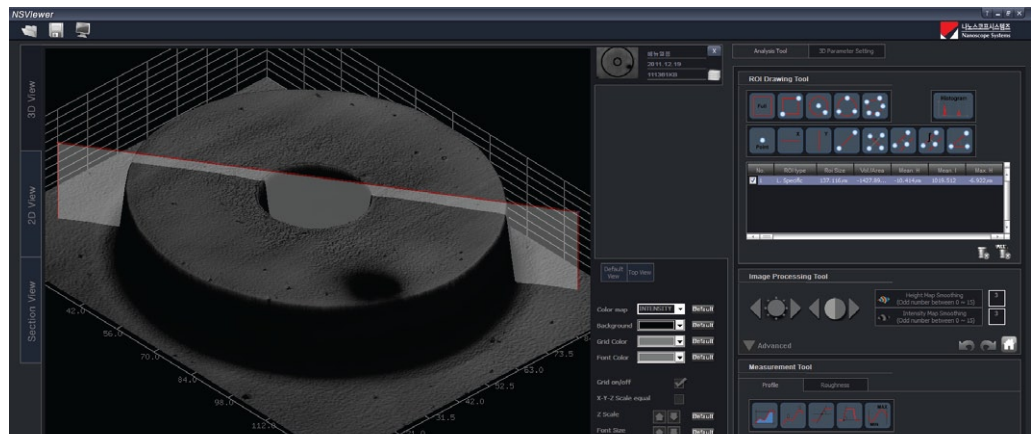
< Operation software *NSWorks* >



< Analysis software *NSViewer* >

Analysis of measurement

Cross-sectional image is directly converted to the 3D profile data. User can see the raw cross-sectional image in *NSViewer*. The internal structure can be imaged through the semi-transparent surface layers, which is uniquely realized only by confocal microscopy. The analysis of the measured data can be easily performed with various function tools.



< Cross sectional image display >

High pass filter setting

High pass filter

5.0 um

Roughness Waviness

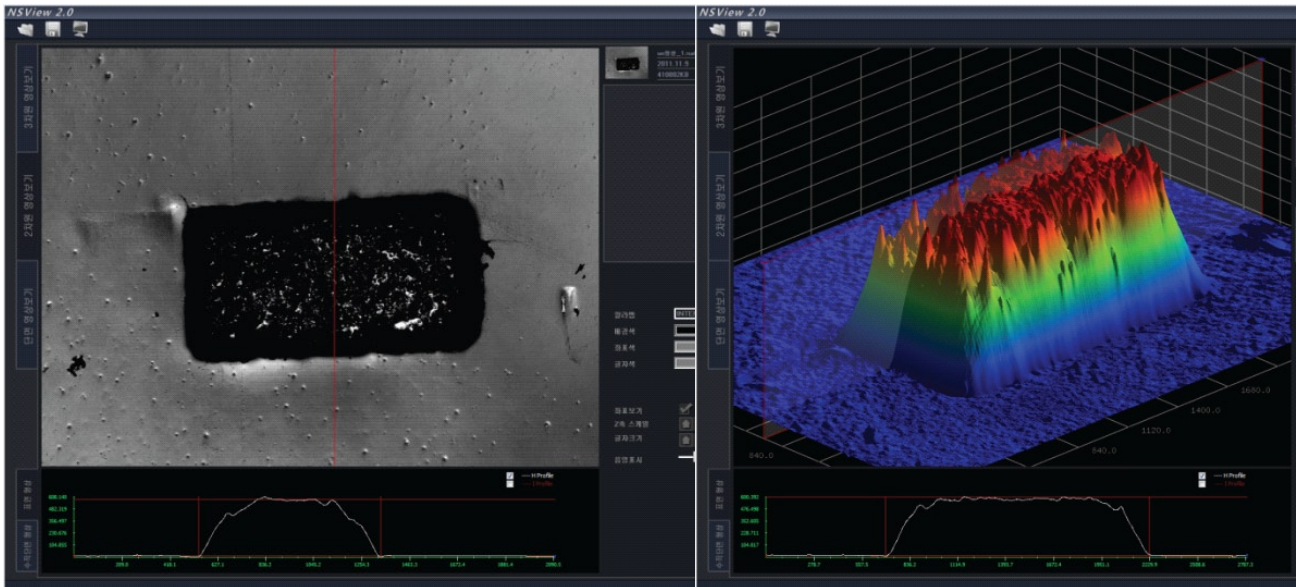
A. Rectangular

| | | | |
|-----|-------|------|--------|
| Ra | 0.344 | Mean | -0.002 |
| Rq | 0.438 | Rp | 5.239 |
| Rsk | 0.066 | Rv | -2.660 |
| Rku | 5.671 | Rt | 7.899 |

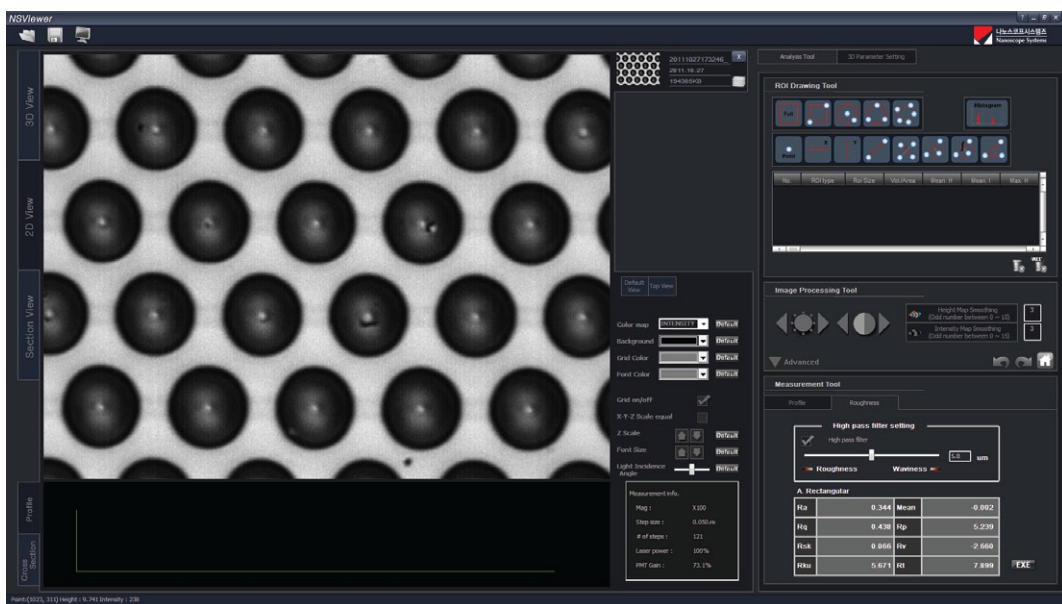
< Roughness measurement for specified ROI (region of interest) >

Most reliable optical 3D measurement

NS-3800 can be used for most kinds of 3D profiling applications. The 3D measurement of NS-3800 is based on the most reliable real-time confocal image definitely superior to the image from other optical technologies.



< Height measurement of the material of very low reflectivity >



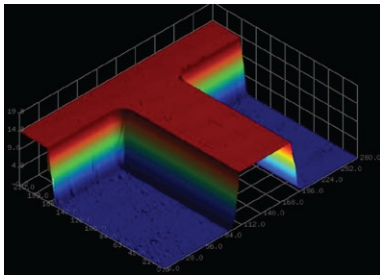
< High contrast image of a patterned sapphire wafer substrate (PSS) >

Application field

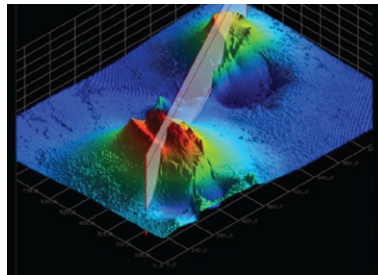
NS-3800 is a promising solution for the measurement of height, width, angle, area, and volume of micro and submicro structures such as

- Semiconductor – IC pattern, bump height, wire loop height, defect inspection, CMP process
- FPD product – Touch panel screen inspection, ITO pattern, LCD column spacer height
- MEMS device – 3D profile of structure, surface roughness, MEMS pattern
- Glass surfaces – Thin film solar cell, solar cell texture, laser pattern
- Material researches – Tooling surface inspection, roughness, crack analysis

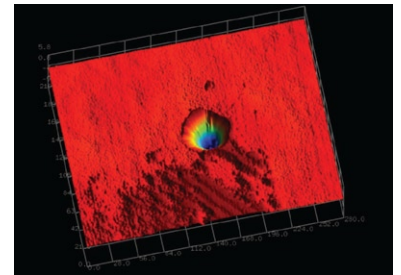
Sample images



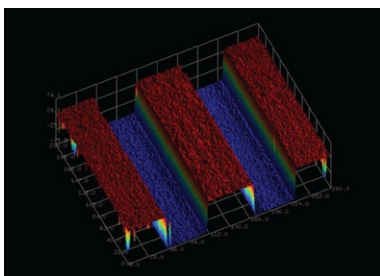
VLSI height standard
FOV : 280 × 210 μm (50×)



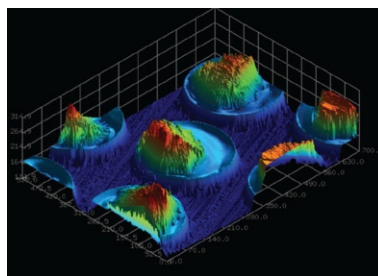
OLED glass protrusion
FOV : 280 × 210 μm (50×)



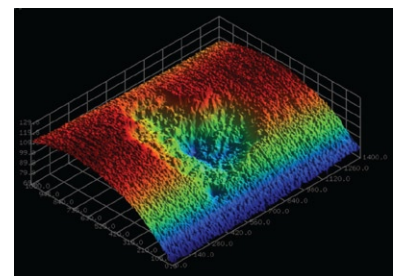
OLED laser processing
FOV : 280 × 210 μm (50×)



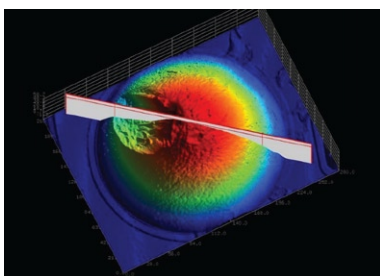
Quartz pattern
FOV : 280 × 210 μm (50×)



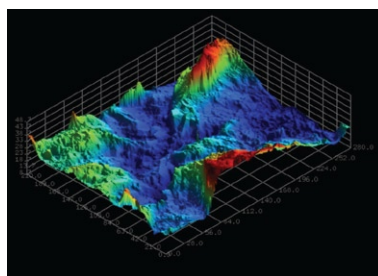
Diamond
FOV : 700 × 525 μm (20×)



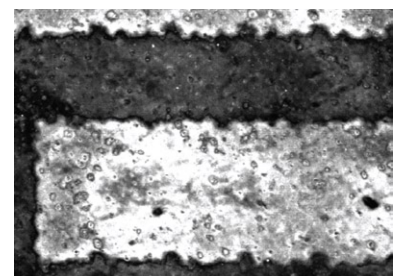
Metal pillar
FOV : 1400 × 1050 μm (10×)



Bump
FOV : 280 × 210 μm (50×)



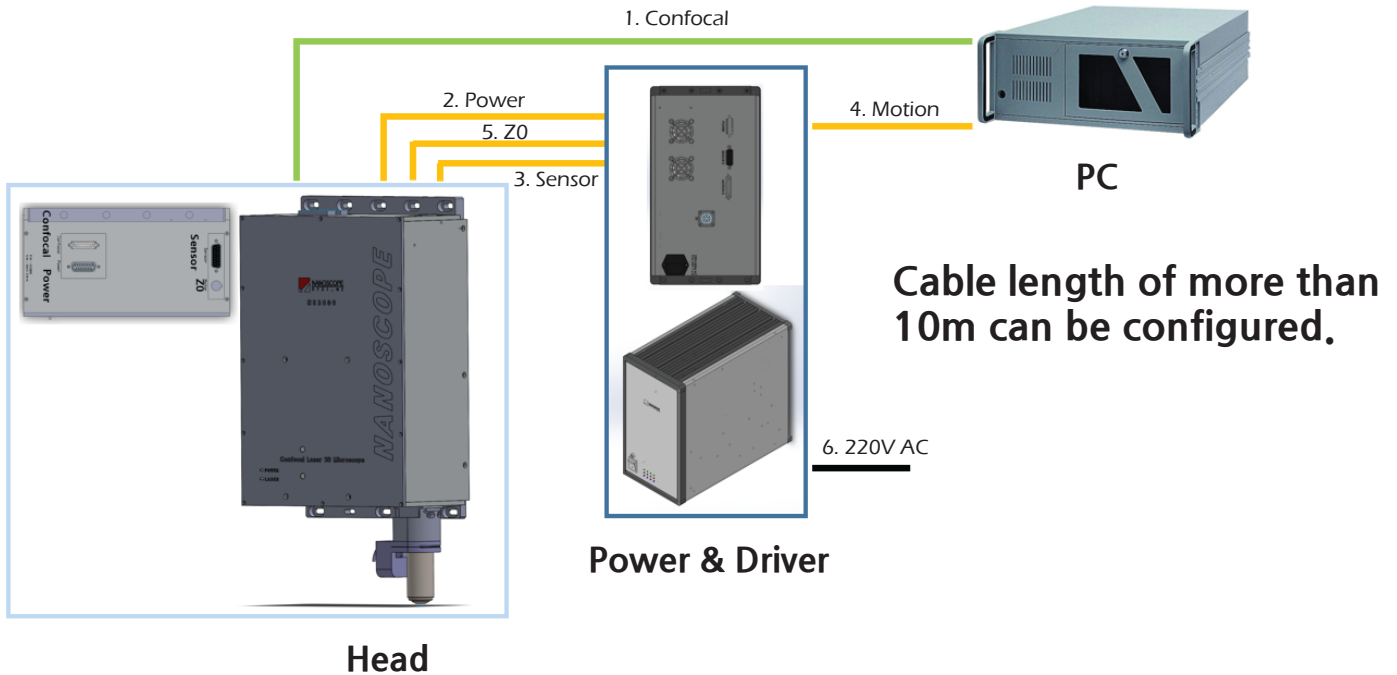
Graphene
FOV : 280 × 210 μm (50×)



ITO pattern
FOV : 1400 × 1050 μm (10×)

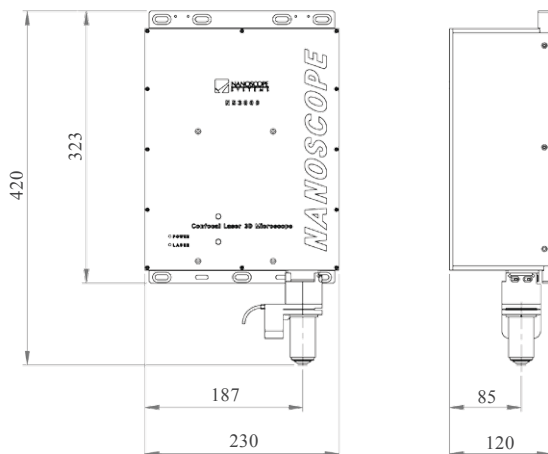
Industrial module application

Easy-to-install, and robust design for industrial equipment provides a good solution to the field applications. Customized design change is available.

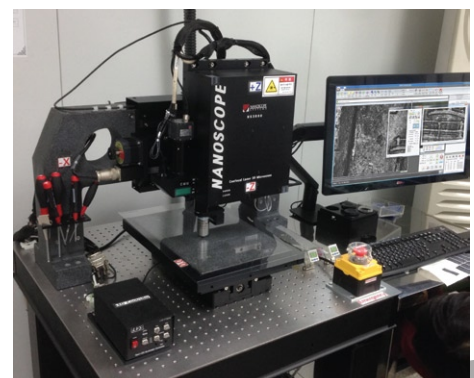


Head dimensions

[Unit : mm]



Installation cases



Specifications

| Model | Head module | NS-3800 | | | | | Remark |
|---|-------------------------------|--|------|------|------|------|--------|
| | Controller | NS-3500E | | | | | |
| Objective lens magnification | | 10× | 20× | 50× | 100× | 150× | |
| Observation / Measuring range | Horizontal (H): μm | 1400 | 700 | 280 | 140 | 93 | |
| | Vertical (V): μm | 1050 | 525 | 210 | 105 | 70 | |
| Working distance: mm | | 16.5 | 3.1 | 0.54 | 0.3 | 0.2 | |
| Numerical aperture (N.A.) | | 0.30 | 0.46 | 0.80 | 0.95 | 0.95 | |
| Optical zoom | | ×1 to ×6 | | | | | |
| Total magnification | | 178× to 26700× | | | | | |
| Optical system for observation / measurement | | Pinhole confocal optical system | | | | | |
| Height measurement | Measuring scan range | <i>Fine scan : 100 μm (and/or) Long scan : 7 mm [NS-3800-L]</i> | | | | | Note 1 |
| | | <i>Fine scan : 400 μm (and/or) Long scan : 10 mm [NS-3800-D]</i> | | | | | |
| | | <i>Fine scan : 200 μm (or) Long scan : 10 mm [NS-3800-T]</i> | | | | | |
| | Display resolution | 0.001 μm | | | | | |
| | Repeatability σ | 0.010 μm | | | | | Note 2 |
| Width measurement | Display resolution | 0.001 μm | | | | | |
| | Repeatability 3σ | 0.02 μm | | | | | Note 3 |
| Frame memory | Pixel count | 1024×768, 1024×384, 1024×192, 1024×96 | | | | | |
| | For confocal image | 12 bit | | | | | |
| | For color image | 8-bit for RGB each | | | | | |
| | For height measurement | 16 bit | | | | | |
| Frame rate | Surface scan | 20 Hz to 160 Hz | | | | | |
| | Line scan | ~8 kHz | | | | | |
| Auto function | | Auto focus | | | | | |
| Laser beam light source for confocal measurement | Wavelength | Violet laser, 405 nm | | | | | |
| | Output | ~2 mW | | | | | |
| | Laser Class | Class 3b | | | | | |
| Laser light-receiving element | | PMT (photomultiplier tube) | | | | | |
| Data processing unit | | Dedicated PC | | | | | |
| Power supply | Power-supply voltage | 100 to 240 VAC, 50/60 Hz | | | | | |
| | Current consumption | 500 VA max. | | | | | |
| Weight | Microscope | Approx. ~ 8 kg | | | | | |
| | Controller | ~8 kg | | | | | |

Note 1 : *Fine scan* is performed by piezoelectric actuator (PZT).

Dual scan mode by *fine* and *long* scanner is available only for single lens type.

Note 2 : 100 times measurement of standard sample (1 μm step height) with 100× / 0.95 objective.

Note 3 : 100 times measurement of standard sample (5 μm pitch) with 100× / 0.95 objective.